UNITED STATES PATENT AND TRADEMARK OFFICE
BEFORE THE PATENT TRIAL AND APPEAL BOARD
INNOLUX CORPORATION Petitioner
V.
PATENT OF SEMICONDUCTOR ENERGY LABORATORY CO., LTD. Patent Owner
CASE IPR2013-00064 PATENT 7,923,311

**RESPONSE OF THE PATENT OWNER** 



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### **EXHIBIT LIST**

#### **Previously filed**

- Exhibit 2001 Complaint, Semiconductor Energy Laboratory Co., Ltd. v. Chimei Innolux Corp., et al., Case No. SACV 12-0021-JST (C.D. Cal).
- Exhibit 2002 Defendants' Motion to Stay Litigation Pending Outcome of Inter Partes Review, *Semiconductor Energy Laboratory Co., Ltd. v. Chimei Innolux Corp., et al.*
- Exhibit 2003 Supplemental Declaration of Gregory S. Cordrey in Support of Defendants' Motion for Stay, *Semiconductor Energy Laboratory Co., Ltd. v. Chimei Innolux Corp., et al.*
- Exhibit 2004 Defendants' Reply in Support of their Motion to Stay, Semiconductor Energy Laboratory Co., Ltd. v. Chimei Innolux Corp., et al.
- Exhibit 2005 Defendant Westinghouse Digital's Notice of Joinder, Semiconductor Energy Laboratory Co., Ltd. v. Chimei Innolux Corp., et al.
- Exhibit 2006 '311 Patent Prosecution History Excerpt Prior Art considered by the Office
- Exhibit 2007 United States Patent No. 4,857,907 (Koden)

### **Currently filed**

- Exhibit 2008 Chun-sung Chiang, Chun-ying Chen, and Jerzy Kanicki, "Investigation of Intrinsic Channel Characteristics of Hydrogenated Amorphous Silicon Thin-Film Transistors by Gated-Four-Probe Structure," Applied Physics Letters, Vol. 72, No. 22, pp. 2874-2876 (1998)
- Exhibit 2009 –U.S. Patent No. 5,270,567 to Mori annotated by Dr. Kanicki
- Exhibit 2010 Chun-ying Chen and Jerzy Kancicki, "High Field-Effect-Mobility a-Si:H TFT Based on High Deposition-Rate PECVD Materials," IEEE Electron Device Letters, Vol. 17, No. 9, pp. 437-439 (1996)
- Exhibit 2011 Declaration of Alex Z. Kattamis, Ph.D.
- Exhibit 2012 Willem den Boer, "Active Matrix Liquid Crystal Displays," Elsevier, Chapter 2, pp. 23-48 (2005).



- Exhibit 2013 Wang et al., "Cu/CuMg Gate Electrode for the Application of Hydrogenated Amorphous Silicon Thin-Film Transistors," Electrochem. Solid-State Lett. Vol. 10 No. 8, pp. J83-J85 (2007).
- Exhibit 2014 Zou, "Anisotropic Si Deep Beam Etching with Profile Control using SF<sub>6</sub>/O<sub>2</sub> Plasma," Microsystem Technologies, Vol. 10, pp. 603–607 (2004)
- Exhibit 2015 Choi et al., "Simple Process for Making New Self-Aligned TFT with Improved On-Current," Electrochemical Society Proceedings, Vol. 96-23, pp. 129-137, 1997
- Exhibit 2016 Uchikoga et al., "The Effect of Contact Overlap Distance on a-Si TFT Performance," Mat. Res. Soc. Symp. Proc., Vol. 258, pp. 1025-1030, 1992
- Exhibit 2017 Kuo et al., "Advanced Multilayer Amorphous Silicon Thin-Film Transistor Structure: Film Thickness Effect on Its Electrical Performance and Contact Resistance," Jpn. J. Appl. Phys. Vol. 47, No. 5, pp. 3362–3367 (2008)
- Exhibit 2018 C. van Berkel, "Amorphous-Silicon Thin-Film Transistors: Physics and Properties, in Amorphous and Microcrystalline Semiconductor Devices," Vol. 2 edited by J. Kanicki, Artech House, pp. 397-447 (1992).
- Exhibit 2019 Chiang et al., "Electrical Instability of Hydrogenated Amorphous Silicon Thin-Film Transistors for Active-Matrix Liquid-Crystal Displays," Jpn. J. Appl. Phys. Vol. 37 pp. 4704-4710 (1998)
- Exhibit 2020 Transcript of Videotaped Deposition of Jerzy Kanicki
- Exhibit 2021 U.S. Patent No. 6,104,042 to Wen-Jyh Sah



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